Application No. 10/579,141 Docket No.: 5376-0101PUS1

## AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the present application.

## Listing of Claims:

- (Currently Amended) A cleaner that is an aqueous solution containing phosphoric
  acid, hydrofluoric acid, and ammonia and/or amine and having a pH ranging from 2 to [[12]] 6,
  wherein said aqueous solution contains:
  - 0.5 to 25 mass% of phosphoric acid,
  - 0.1 to 10 mass% of ammonia and/or amine, and
  - [[5×10<sup>-3</sup>]] 0.1 to 5.0 mass% of hydrofluoric acid.
- (Previously Presented) The cleaner according to claim 1, wherein the pH is regulated by phosphoric acid.
- (Original) The cleaner according to claim 1 or 2, which further includes a surface active agent and/or a chelate agent.
- (Previously Presented) The cleaner according to claim 1, which further includes hydrogen peroxide.

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 (Previously presented) The cleaner according to claim 1, which is used for cleaning off particles and/or metal impurities out of the surface of a semiconductor device substrate.

- (Previously Presented) The cleaner according to claim 2, which further includes hydrogen peroxide.
- (Previously Presented) The cleaner according to claim 3, which further includes hydrogen peroxide.
- (Previously presented) The cleaner according to claim 2, which is used for cleaning off particles and/or metal impurities out of the surface of a semiconductor device substrate.
- (Previously presented) The cleaner according to claim 3, which is used for cleaning off particles and/or metal impurities out of the surface of a semiconductor device substrate.
- (Previously presented) The cleaner according to claim 4, which is used for cleaning off particles and/or metal impurities out of the surface of a semiconductor device substrate